

	U	1	PT	P	Document ID	Issue Date	Pages
1	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020089332 A1	20020711	9
2	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 5825035 A	19981020	58
3	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 5583344 A	19961210	43
4	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 5504340 A	19960402	45
5	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 5426299 A	19950620	9
6	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 5223711 A	19930629	8
7	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 5185523 A	19930209	8
8	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 4714891 A	19871222	32
9	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20030049937 A	20030312	12
10	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	EP 960431 B	19980820	1
11	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	JP 06101040 A	19940412	5

	Title	Current OR	Current XRef
1	Probe assembly for detecting an ion in a plasma generated in an ion source	324/466	
2	Processing method and apparatus using focused ion beam generating means	250/423R	250/492.21; 315/111.41; 315/111.81
3	Process method and apparatus using focused ion beam generating means	250/492.21	250/423R
4	Process method and apparatus using focused ion beam generating means	250/492.21	250/309; 250/423R
5	Inductive plasma mass spectrometer	250/281	250/283; 250/286; 250/299; 250/300; 250/397
6	Plasma sources mass spectrometry	250/281	250/282; 250/283; 250/397
7	Mass spectrometer for analyzing ultra trace element using plasma ion source	250/281	250/282; 250/288
8	Method and apparatus for improving the safety and extending the range of ionization gauge systems	324/459	307/326; 324/500; 361/42
9	Substrate surface treatment apparatus for executing surface treatment to a substrate in a reaction chamber, comprises detecting device, and controller for controlling reduction of energy of ions in plasma		
10	Element selective detection - with a micro plasma mass spectrometer having a plasma ion source in the high vacuum chamber		
11	Ion implantation appts. - in which peak current density of ion beam is decreased by adjusting gap distance between ion source plasma chamber and drawing out pole		

	Retrieval Classif	Inventor	S	C	2	3	4	5
1		Benveniste, Victor M.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
2		Mizumura, Michinobu et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
3		Mizumura, Michinobu et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
4		Mizumura, Michinobu et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
5		Nakagawa, Yoshitomo et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
6		Sanderson, Neil E. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
7		Kitagawa, Masatoshi et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
8		Morrison, Jr., Charles F.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
9		NISHIDA, K et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
10		BREDE, C et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
11			<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>

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1	US 20020089332
2	US 5825035
3	US 5583344
4	US 5504340
5	US 5426299
6	US 5223711
7	US 5185523
8	US 4714891
9	US 20030049937
10	EP 960431 A0
11	JP 06101040 A

	U	1	PT	P	Document ID	Issue Date	Pages
12	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	WO 9102376 A	19910221	8

	Title	Current OR	Current XRef
12	Plasma source mass spectrometer - has inductively or microwave coupled source and mass filter and low collector shielded from neutral particles		

	Retrieval Classif	Inventor	S	C	2	3	4	5
12		SANDERSON, N E et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>

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12	US 5223711

	Type	L #	Hits	Search Text	DBs	Time Stamp
1	BRS	L1	12	(plasma adj10 chamber) adj30 (detect\$3 adj10 ion\$1)	USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2003/10/14 10:55